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3-17-01
J. Antai

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :
Moshe FINAROV :
Serial No. Not yet assigned : Group Art Unit: Not yet assigned
Filed: July 26, 2000 : Examiner:

For: AN APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR
PROCESS CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND A
METHOD FOR USE THEREOF

PRELIMINARY AMENDMENT

Assistant Commissioner For Patents
Washington, D. C. 20231

Sir:

Preliminary to examination of the above-referenced application, please amend the
application:

IN THE SPECIFICATION:

On page 1, after the title, please insert the following:

--The present application is a continuation-in-part of U.S. Application Serial No.
09/509,080 filed March 22, 2000, entitled AN APPARATUS FOR INTEGRATED
MONITORING OF WAFERS AND FOR PROCESS CONTROL IN THE SEMICONDUCTOR
MANUFACTURING AND A METHOD FOR USE THEREOF--.

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